

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In Re Application of: |) | |
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| Liang, Ted et al. |) | |
| |) | |
| U.S. Serial No: 09/895,511 |) | Examiner: Zervigon, Rudy |
| |) | |
| Filed: June 29, 2001 |) | Art Unit: 1763 |
| |) | |
| For: APPARATUS FOR ELECTRON |) | |
| BEAM-INDUCED CHEMICAL |) | |
| <u>ETCHING</u> |) | |

Mail Stop Amendment
Commissioner for Patents
P. O. 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE

Dear Sir:

This is in response to the Office Action mailed on April 24, 2006. Applicants respectfully request the Examiner to enter the following amendments and consider the following remarks.